

MAY 20 2004

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 213.002-D1-US)

In the Application of: Ye et al.

Serial No: 10/646,313

Filed: August 22, 2003

Title: **System and Method for Lithography
Process Monitoring and Control**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

) Group Art Unit: 2878

) Before Examiner: Que Tan Le

I hereby certify that this correspondence is
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Date

Neil Steinberg
(name of person signing this certificate)

[Signature]
Signature

AMENDMENT

Dear Sir:

Kindly amend the above-referenced application as follows: